

FIG. 1

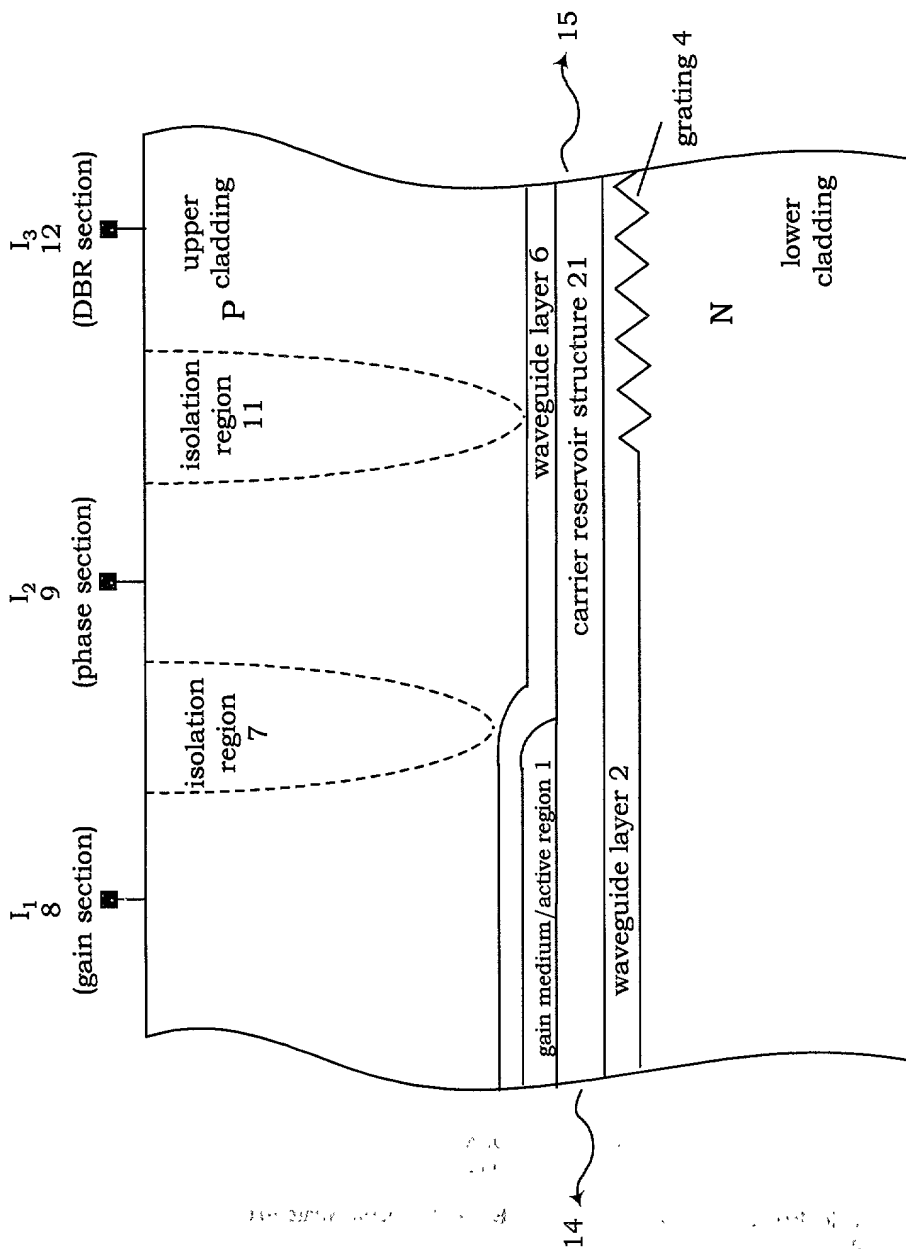


FIG. 2

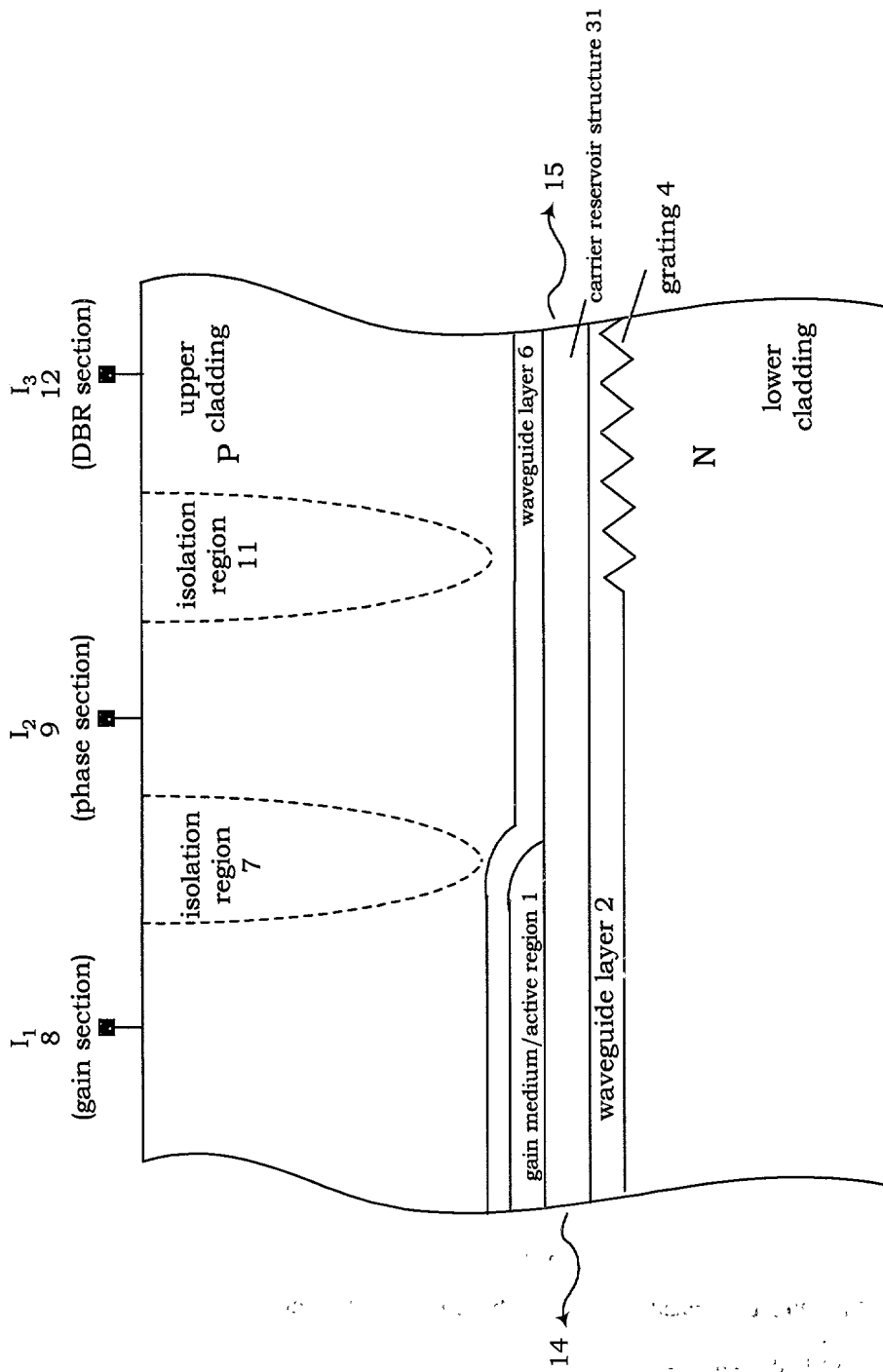


FIG. 3

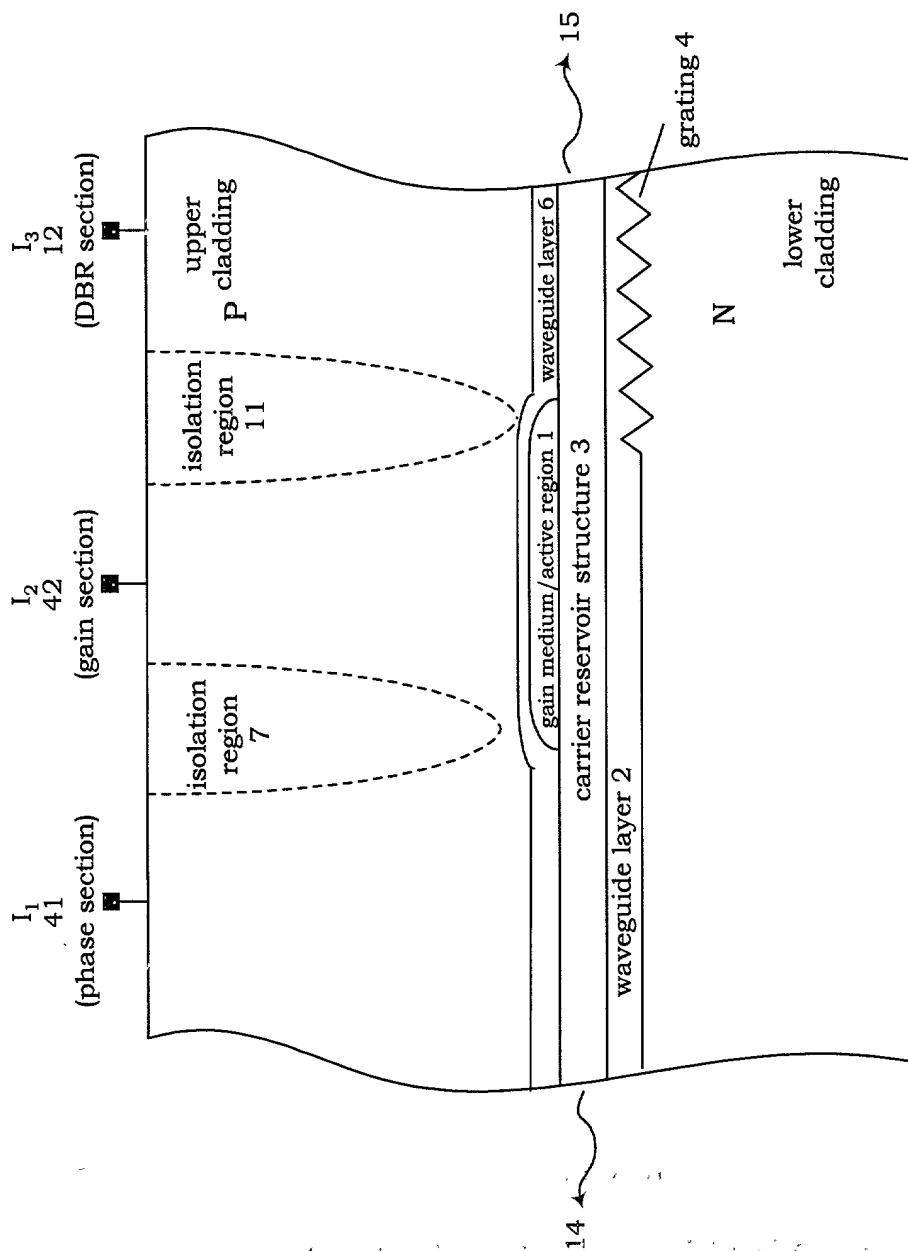
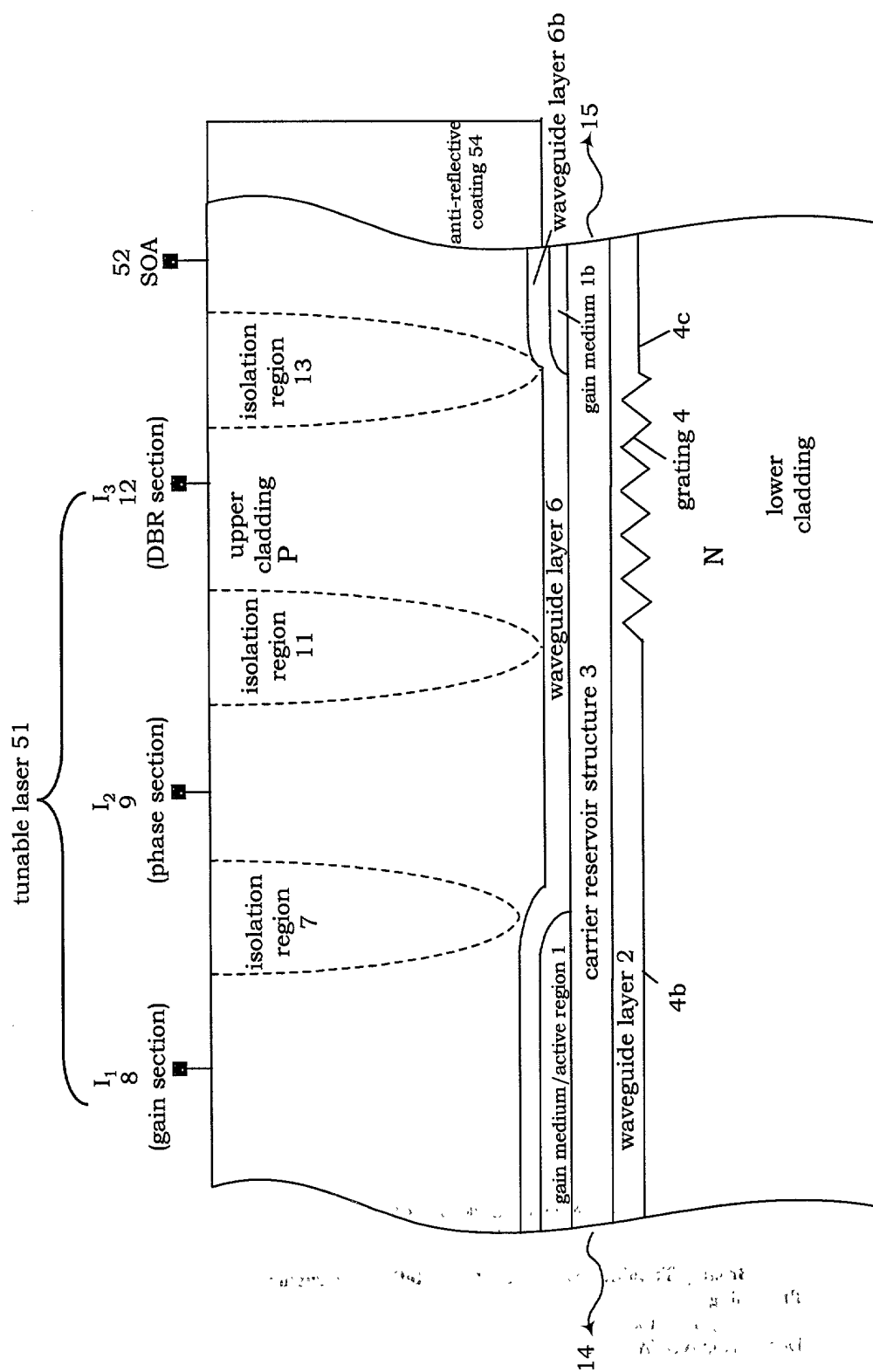


FIG. 4



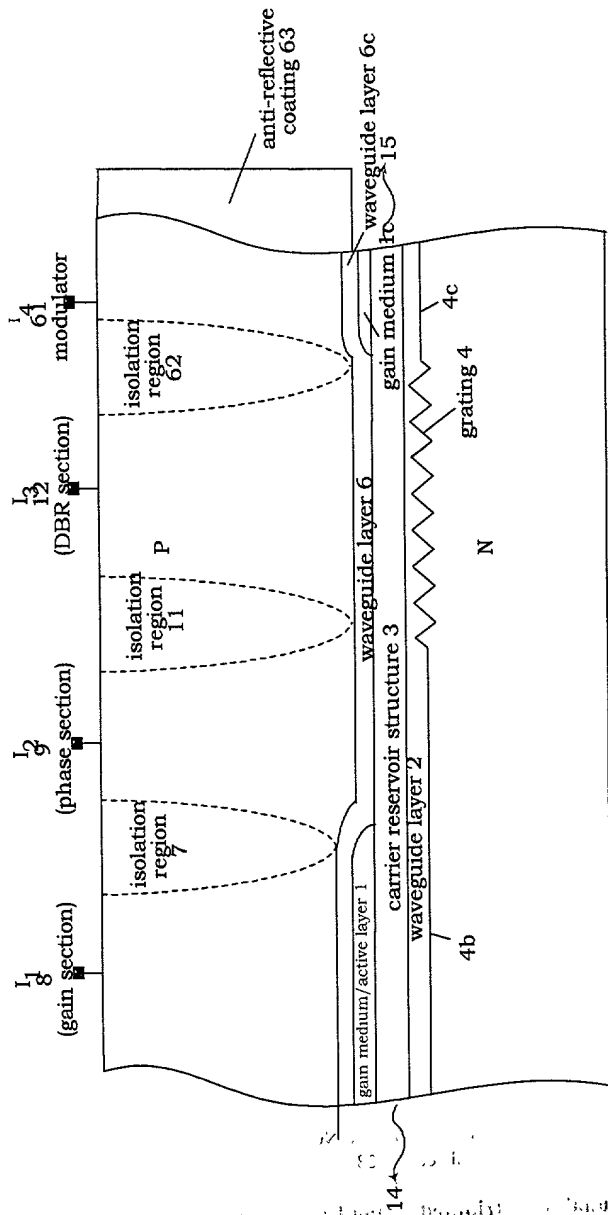


FIG. 6

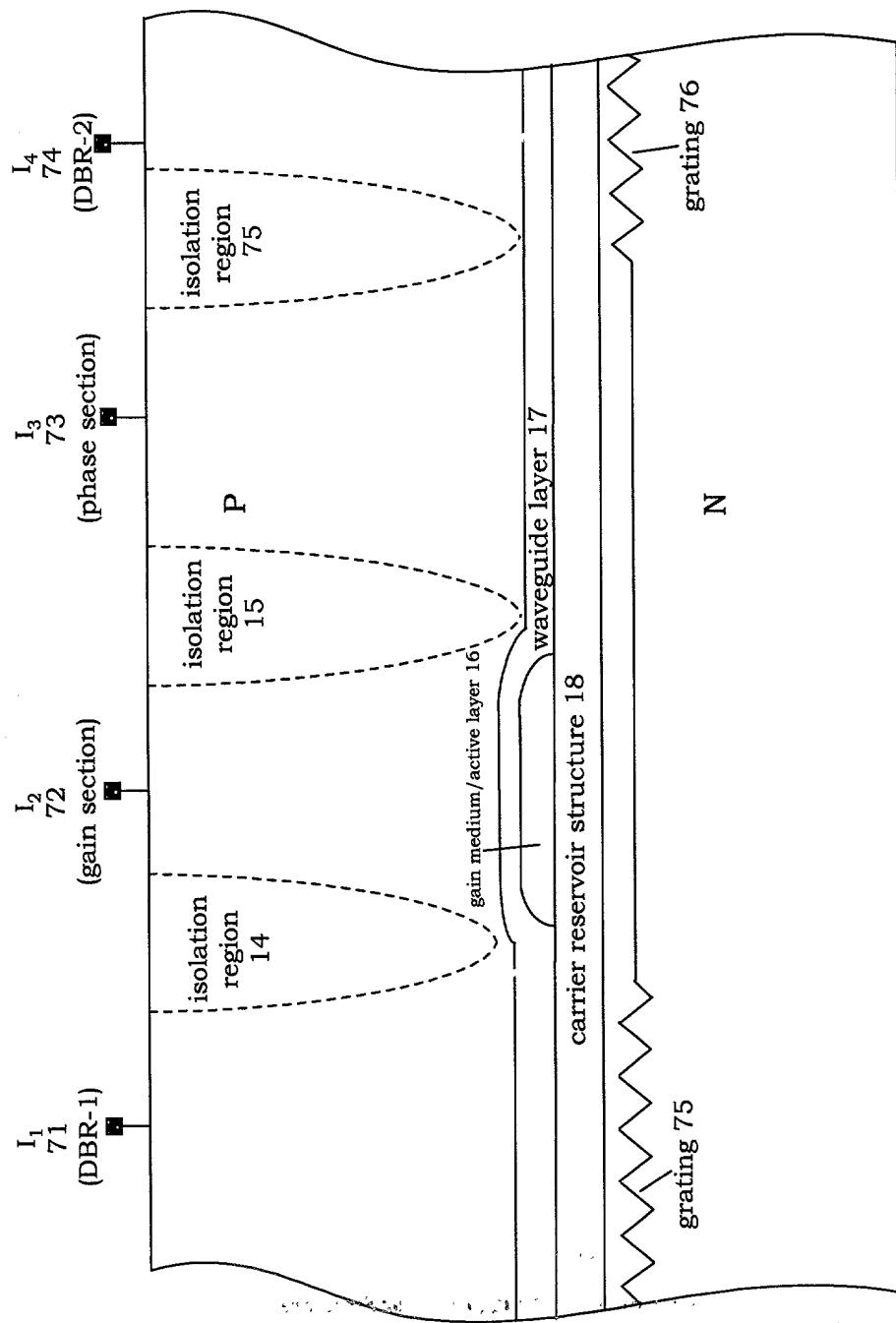
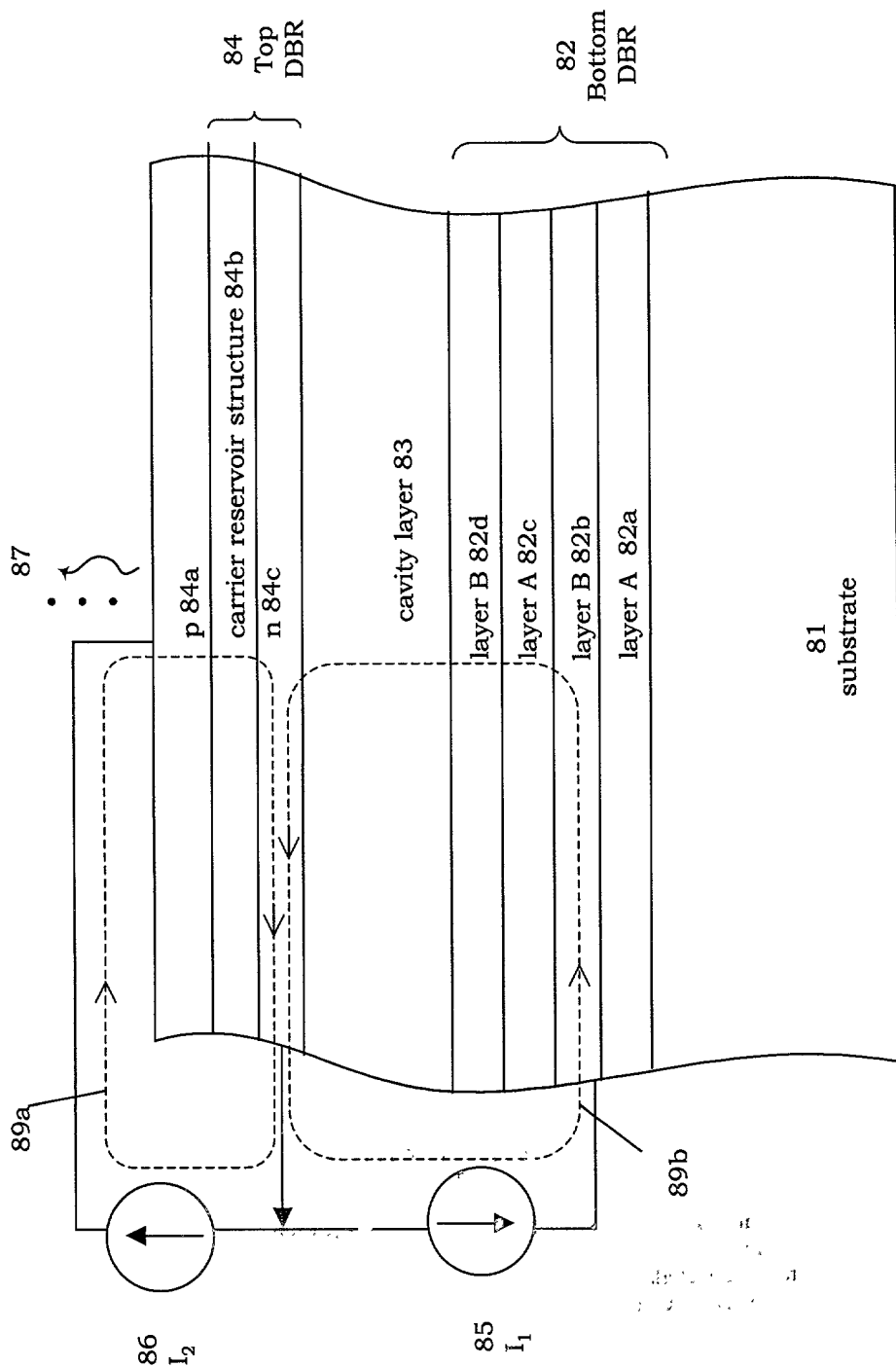
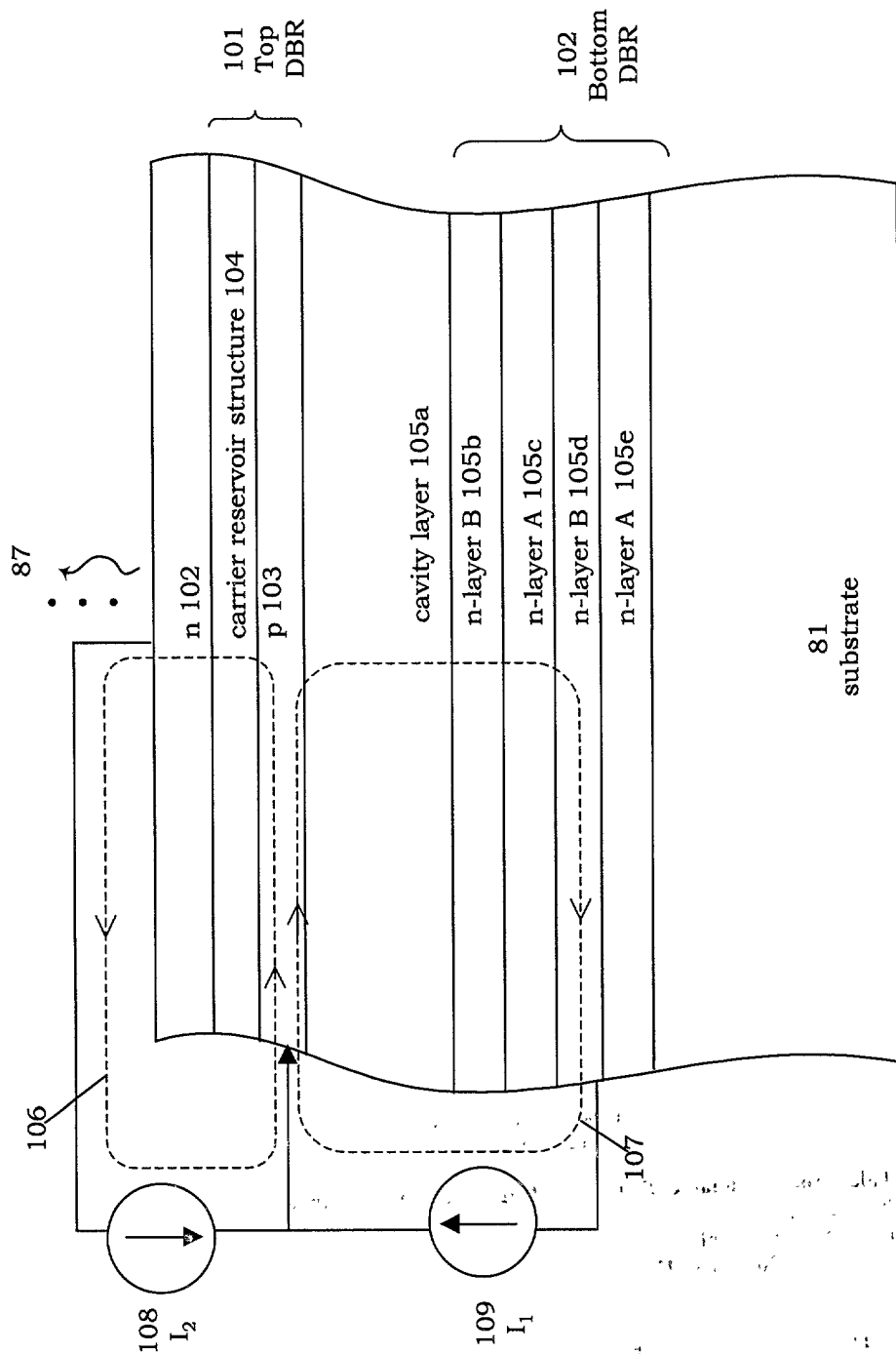


FIG. 7





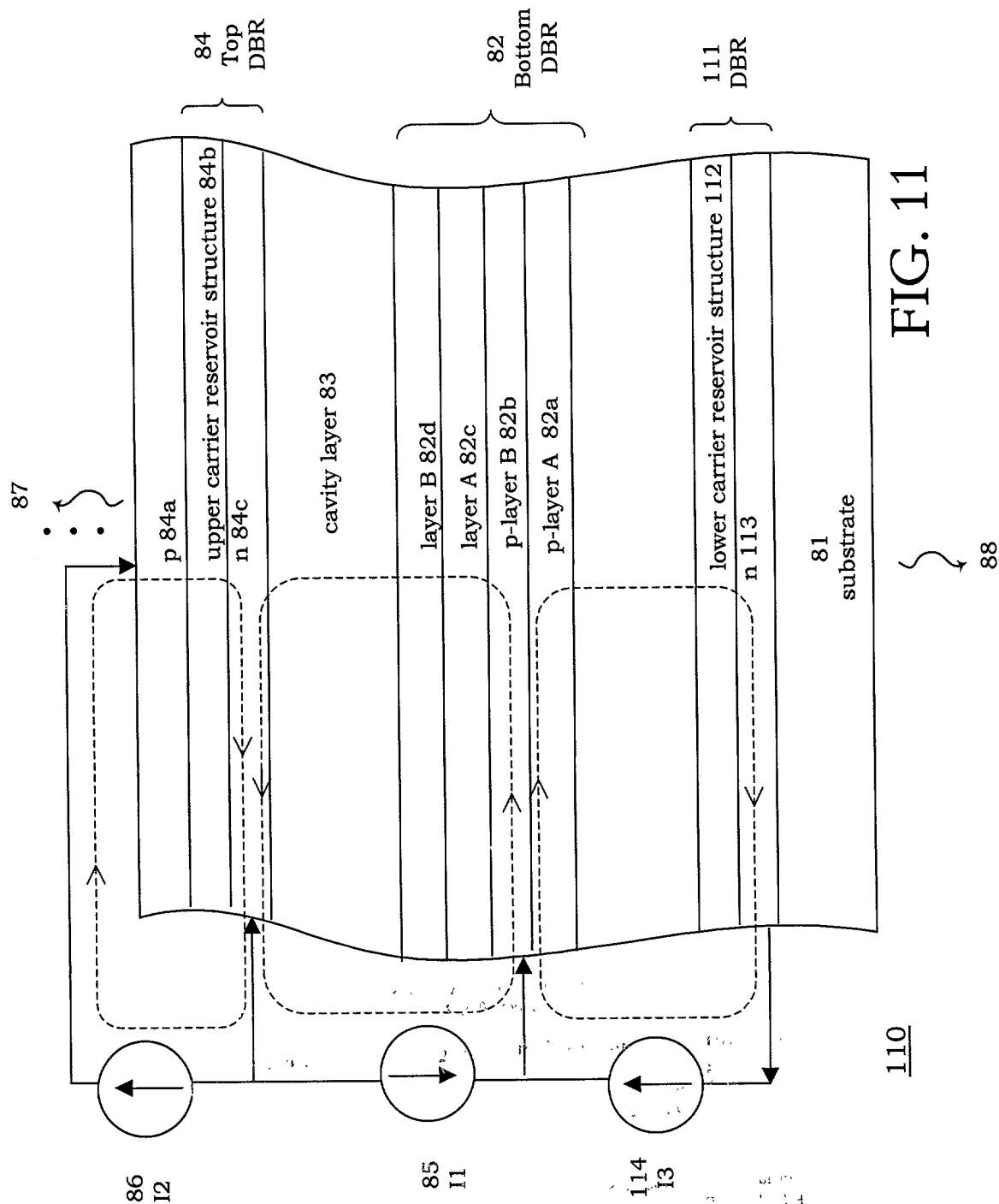
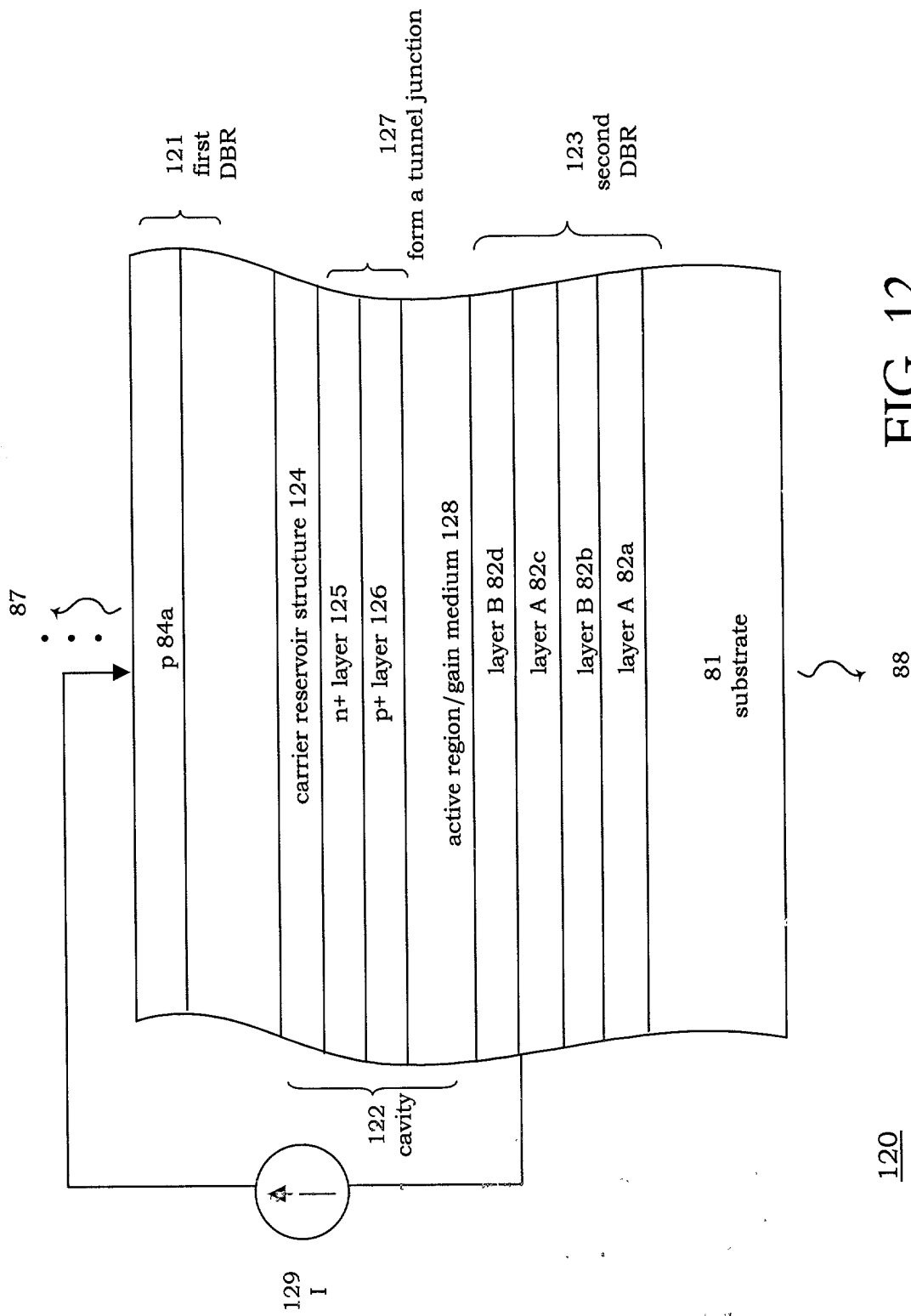
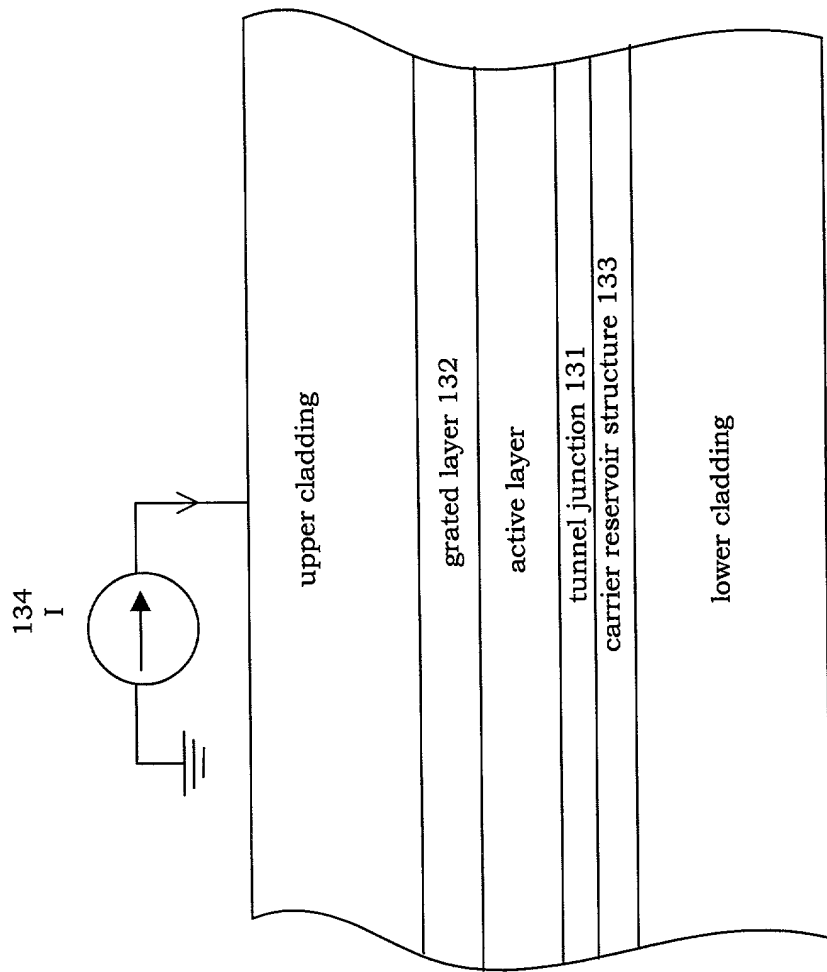


FIG. 11





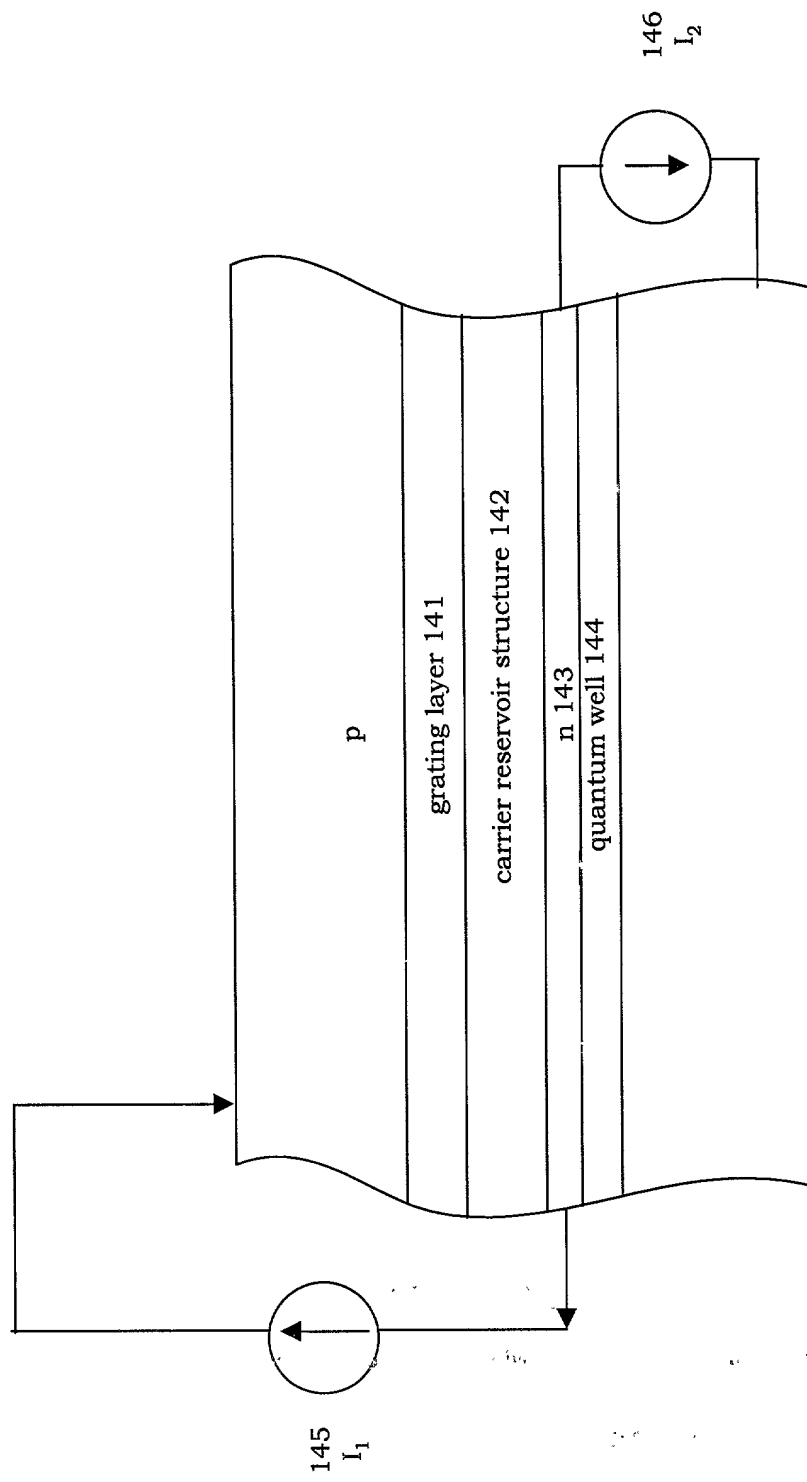


FIG. 14

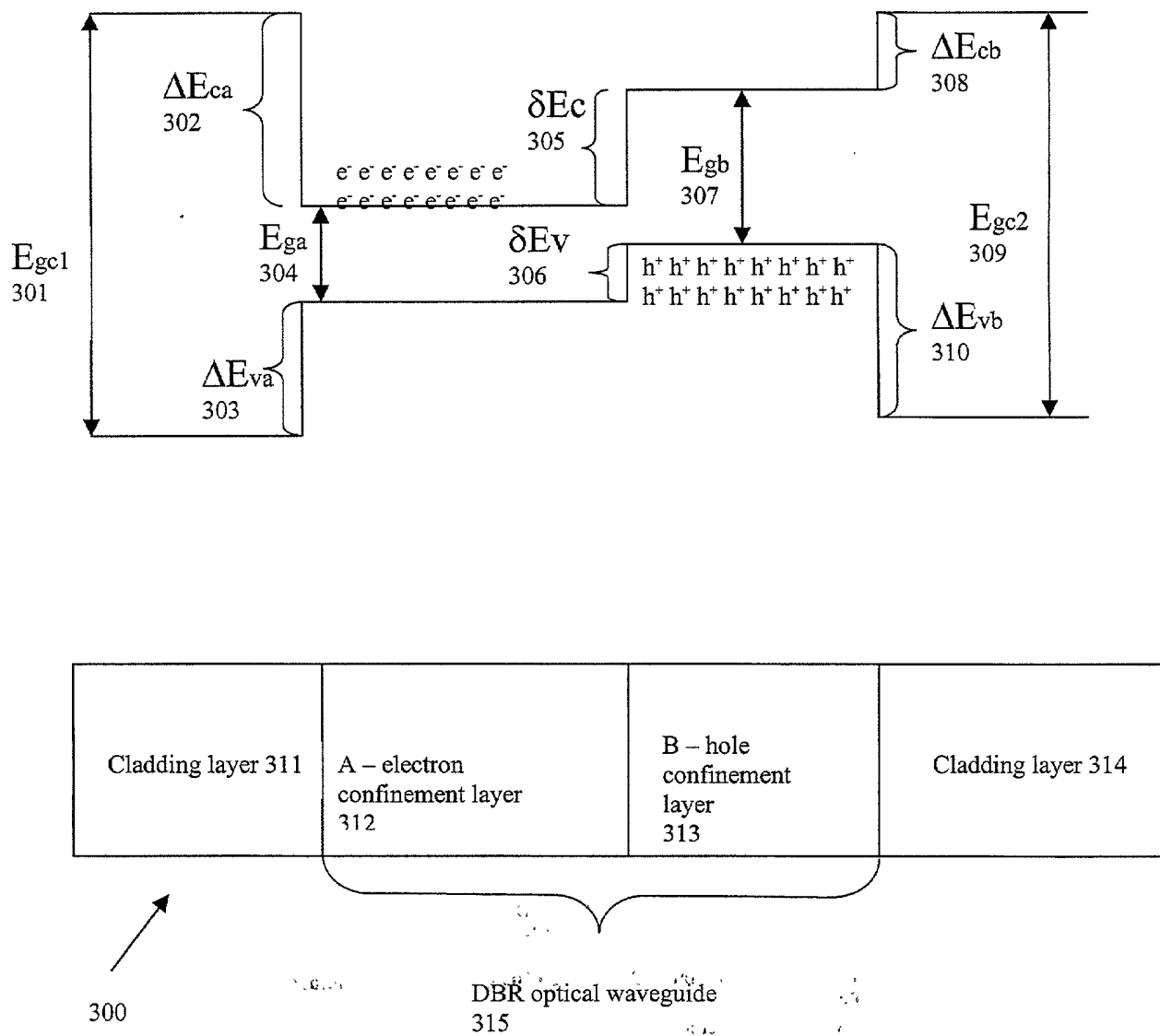
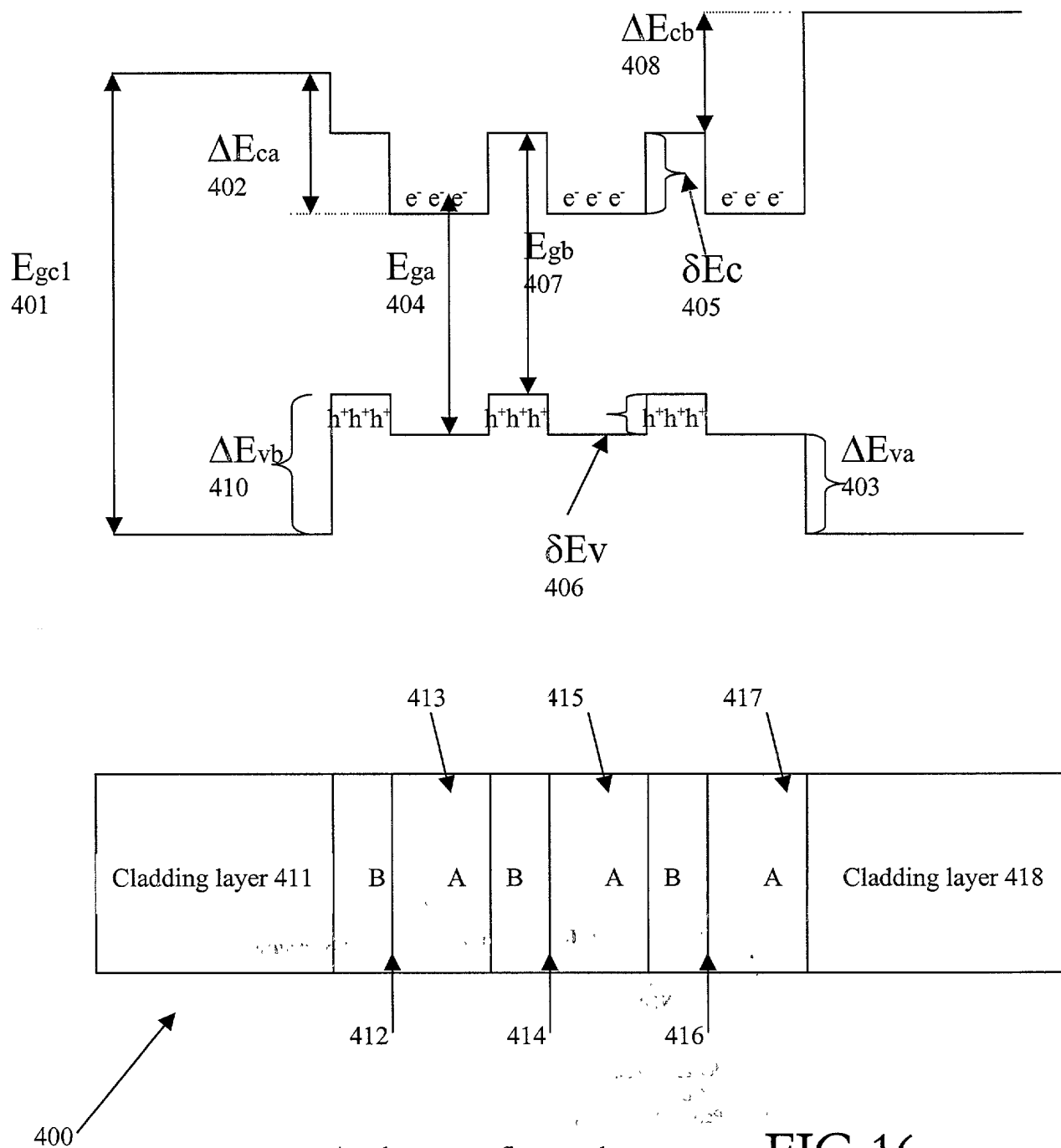


FIG. 15



A= electron confinement layer
B= hole confinement layer

FIG.16

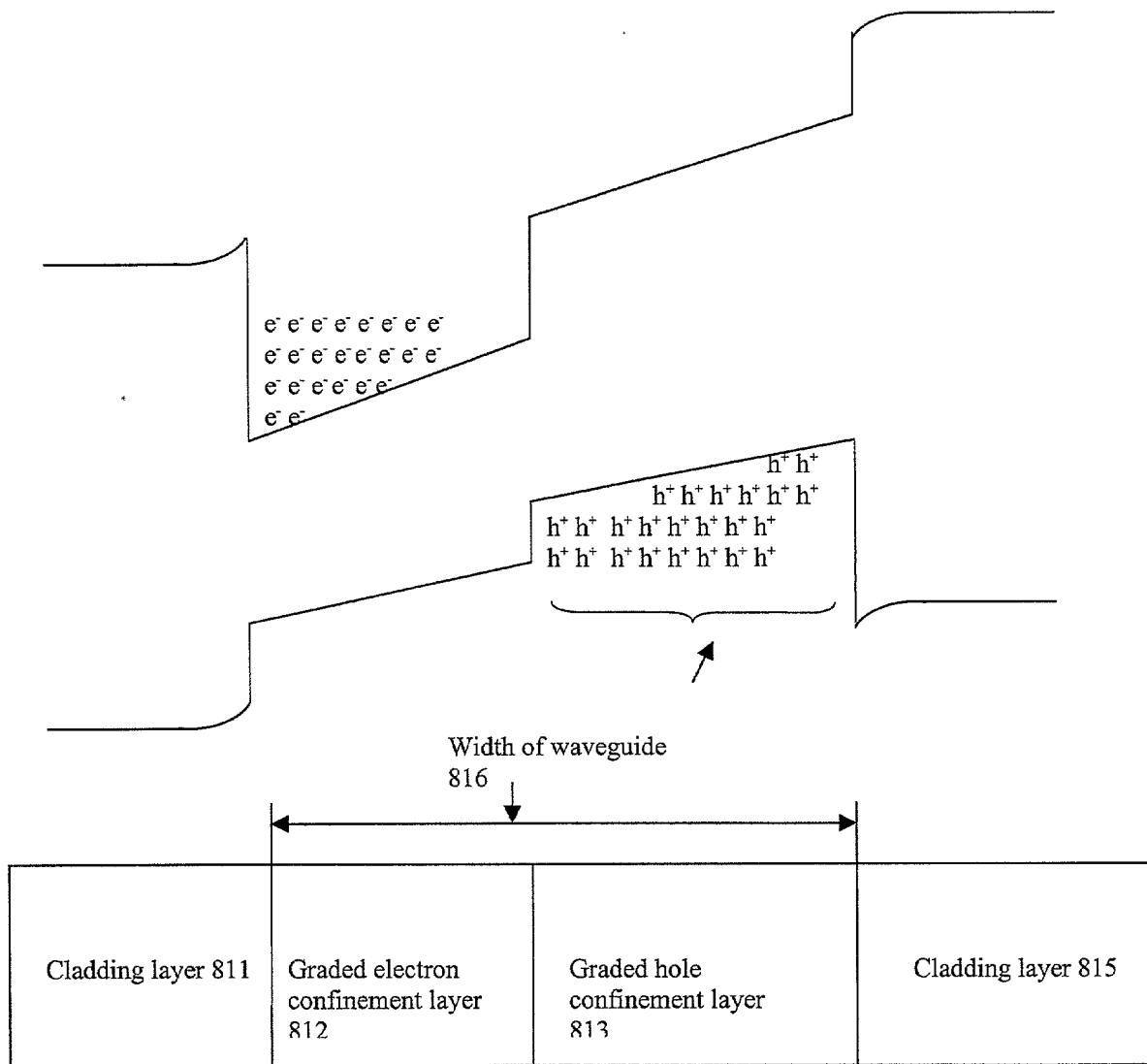


FIG. 17

FIG. 18

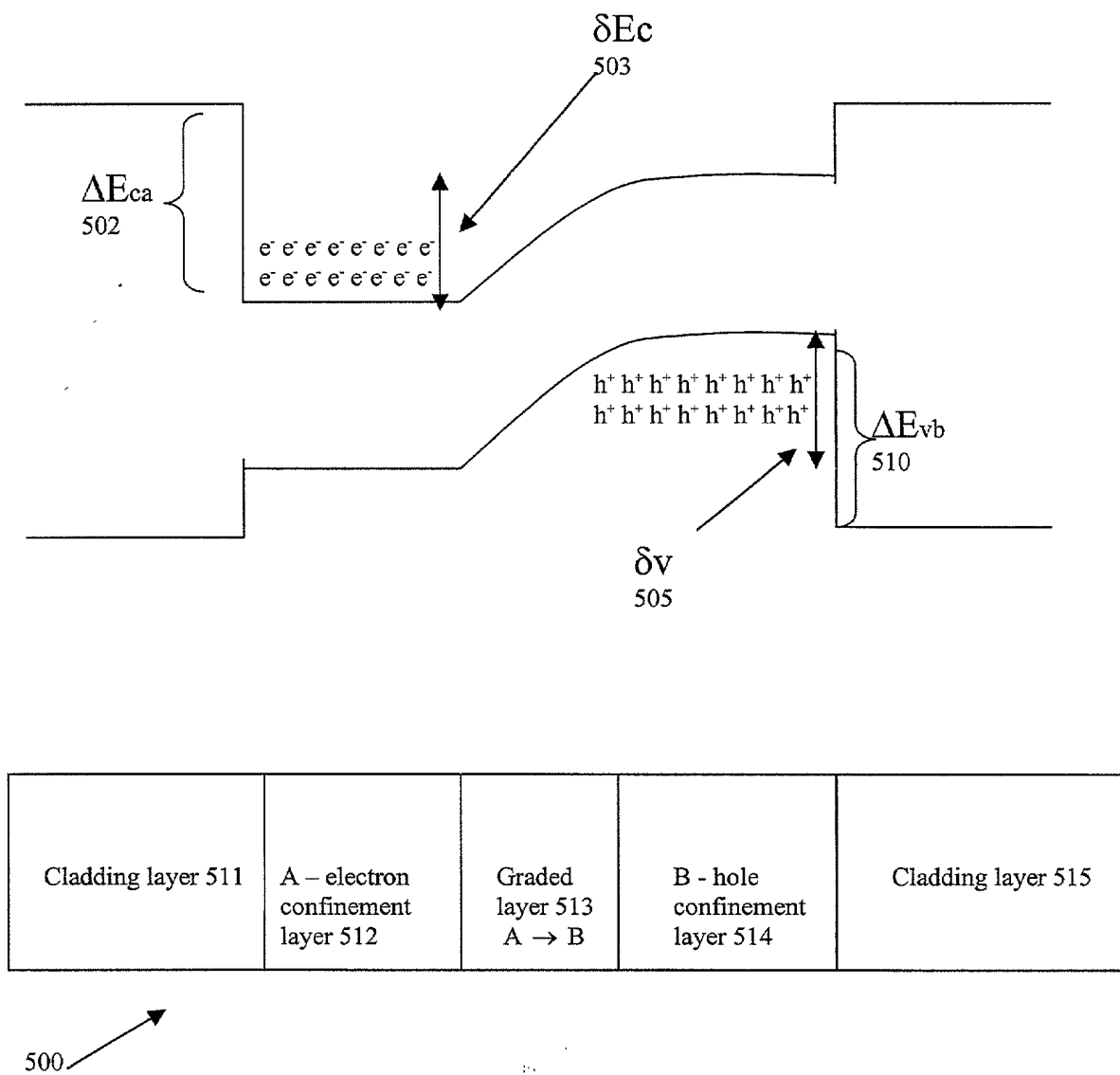


FIG. 18

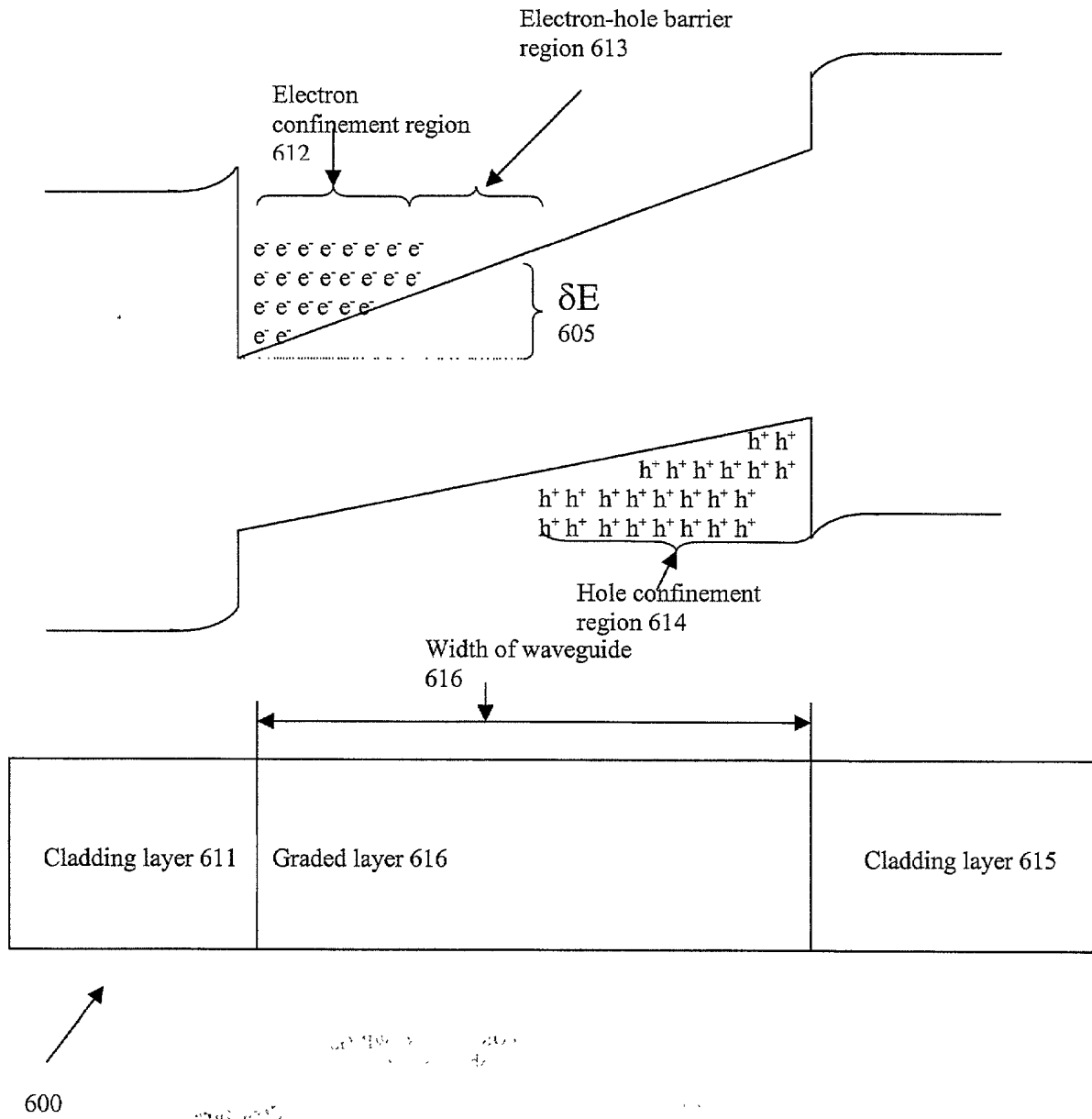


FIG. 19

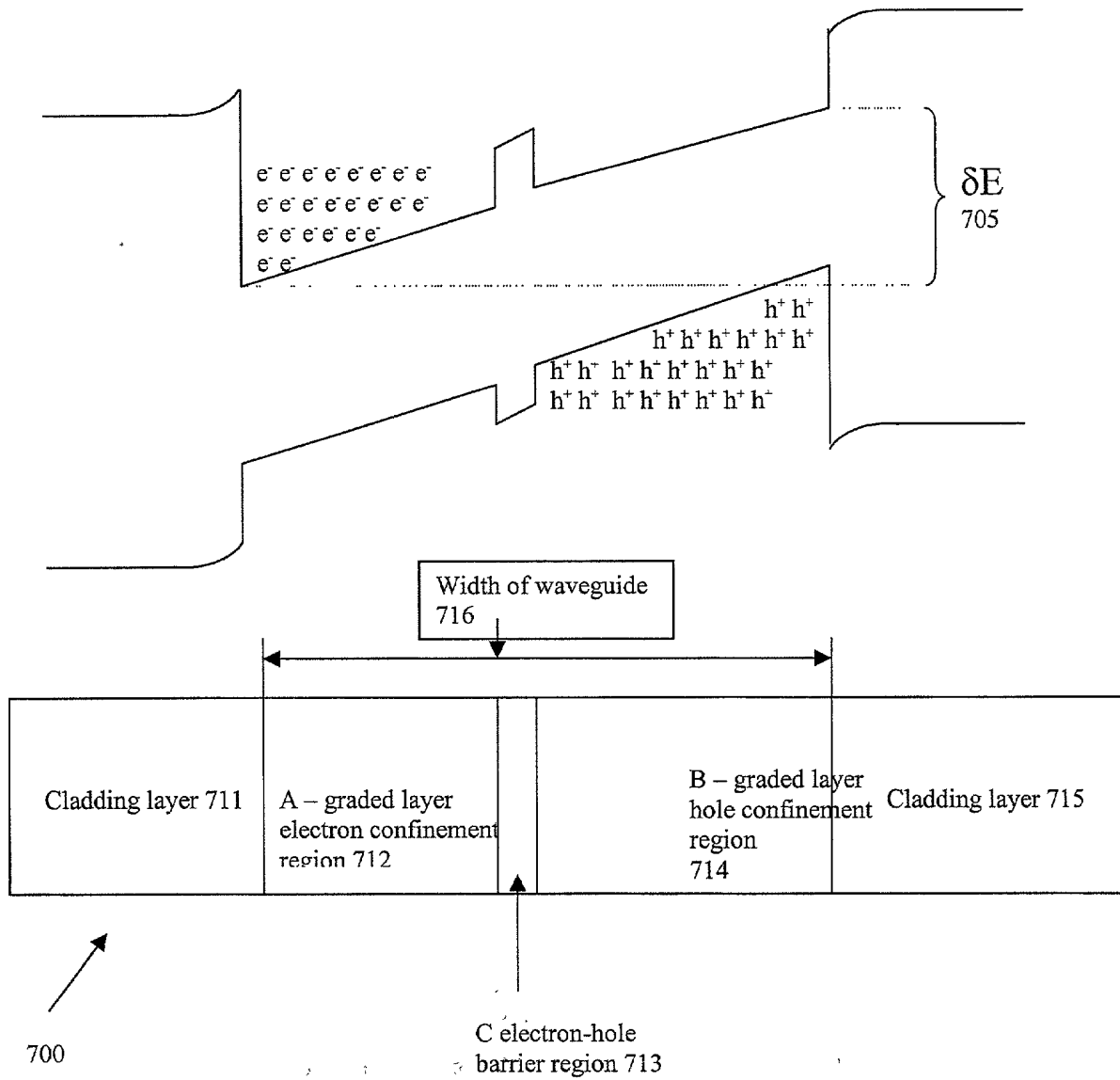


FIG. 20

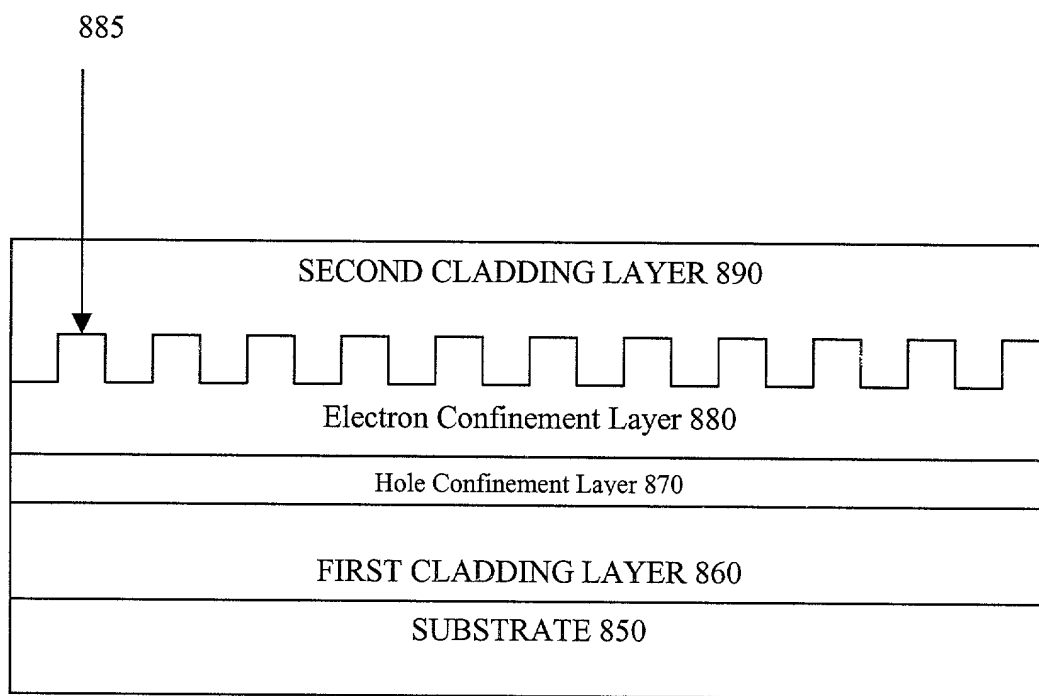


FIG. 21

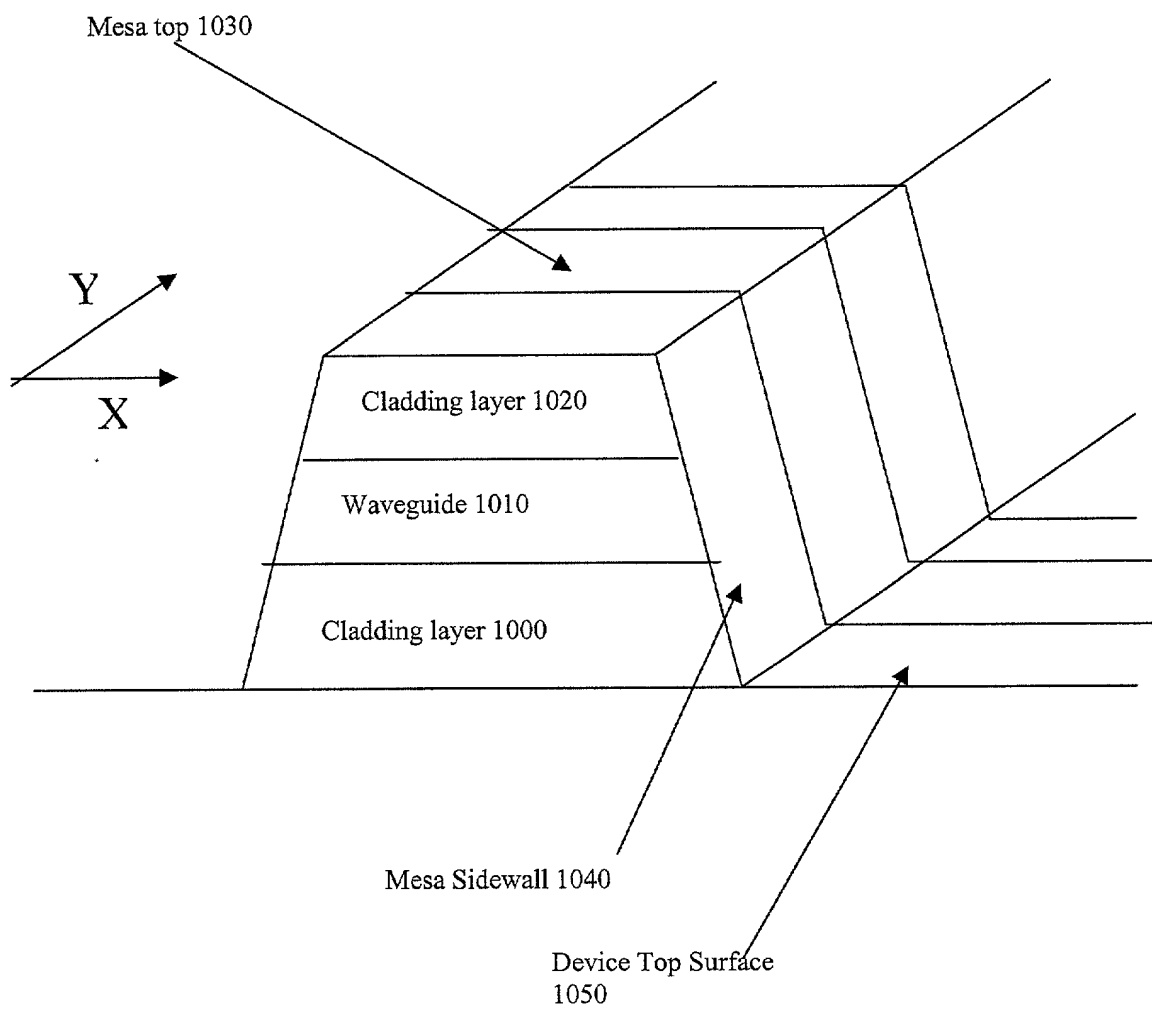


FIG. 22

Create a first cladding layer (Step 910).



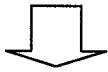
Create a grating layer (Step 920).



Create a hole confinement region layer (Step 930).



Create an electron confinement region layer (Step 940).



Create a second cladding layer (Step 950).



(Optional) Pattern laser structure and additional device processing (Step 960).

FIG. 23